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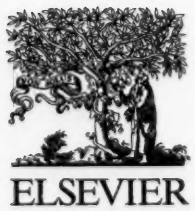

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Contents

Volume 78 Number 1

AUTHORS		ARTICLES
L.-J. Wang and F. Chau-Nan Hong	1	Surface structure modification on the gas separation performance of carbon molecular sieve membranes
A. Vesel, M. Mozetic, M. Zumer, V. Nemanic and B. Zajec	13	Pressure/current characteristics of a magnetron cold cathode gauge
M.A. Vasylyev, S.P. Chenakin and V.A. Tinkov	19	Electron energy loss spectroscopy study of the effect of low-energy Ar+-ion bombardment on the surface structure and composition of $Pt_{80}Co_{20}$ (111) alloy
H. Han, S. Baba, H. Kitagawa, S. Abu Suilik, K. Hasezaki, T. Kato, K. Arakawa and Y. Noda	27	Plasma-carburization of nickel-based self-fluxing alloy
P. Gnanadurai, N. Soundararajan and C.E. Sooriamoorthi	33	Influence of heating rate on the hysteresis in the phase transition in silver selenide thin films
J.O. Carneiro, V. Teixeira, A. Portinha, L. Dupák, A. Magalhães and P. Coutinho	37	Study of the deposition parameters and Fe-dopant effect in the photocatalytic activity of TiO_2 films prepared by dc reactive magnetron sputtering
A. Sharma, P. Bhatt, R. Brajpuriya, S. Tripathi and S.M. Chaudhari	47	Correlation study between structural, magnetic and transport properties of annealed Co thin films
W. Zhao-yang, H. Li-zhong, Z. Jie, S. Jie and W. Zhi-jun	53	Effect of the variation of temperature on the structural and optical properties of ZnO thin films prepared on Si (111) substrates using PLD
B. Kułakowska-Pawlak, J. Walkowicz, W. Żyrnicki and J. Smolik	59	Plasma parameters in some industrial vacuum arc deposition systems
D. Devia, R. Ospina, V. Benavides, E. Restrepo and A. Devia	67	Study of TiN/BN bilayers produced by pulsed arc plasma
J.M. Lackner	73	Industrially-styled room-temperature pulsed laser deposition of titanium-based coatings
S. Abdel-Samad, M. Abdel-Bary and K. Kilian	83	Residual gas analysis in the TOF vacuum system
S. Lee, Y. Moon, J. Lee, J. Yoon, J.-H. Moon, J.-h. Kim, S.-H. Yoo and H. Chung	91	Analytical and finite element method design of quartz tuning fork resonators and experimental test of samples manufactured using photolithography 2: comprehensive analysis of resonance frequencies using Sezawa's approximations
J. Wang, J. Shao, K. Yi and Z. Fan	107	Layer uniformity of glancing angle deposition

Volume 78 Numbers 2–4

L. Michalak, D. Mączka and J. Żuk	**113**	Editorial
R. López-Callejas, R. Valencia-Alvarado, S.R. Barocio, A.E. Muñoz-Castro, A. Mercado-Cabrera, O.G. Godoy-Cabrera and A. de la Piedad-Beneitez	**115**	Dependence of nitrogen implantation by the PIII process at low energy on pressure and temperature
Y.A. Bumai, D.S. Bobuchenko, A.N. Akimov, L.A. Vlasukova and A.R. Filipp	**119**	Optical properties of GaN synthesized by implantation of nitrogen ions into GaAs
J. Piekoszewski, W. Kempinski, B. Andrzejewski, Z. Trybuła, L. Piekara-Sady, J. Kaszyński, J. Stankowski, Z. Werner, E. Richter, F. Prokert, J. Stanisławski and M. Barlak	**123**	Superconductivity of MgB_2 thin films prepared by ion implantation and pulsed plasma treatment
G. Brauer, W. Anwand, P.G. Coleman and W. Skorupa	**131**	Slow positron implantation spectroscopy—a tool to characterize vacancy-type damage in ion-implanted 6H-SiC
S. Ahmed, K. Amirov, U. Larsson, J. Lin, A. Haq, P. Too and Z. Tabatabaian	**137**	Implantation induced interdiffusion of InGaAs quantum dots-effect of ion species, dose and substrate temperature
J. Baszkiewicz, D. Krupa, J. Mizera, J.W. Sobczak and A. Biliński	**143**	Corrosion resistance of the surface layers formed on titanium by plasma electrolytic oxidation and hydrothermal treatment
K. Reszka, J. Rakoczy, Z. Żurek, A. Czyżniewski, A. Gilewicz and M. Homa	**149**	Catalytic properties of Al_2O_3 deposited by ion sputtering using DC and RF sources
V.M. Astashynski, S.I. Ananin, V.V. Askerko, E.A. Kostyukevich, A.M. Kuzmitski, V.V. Uglov, N.N. Cherenda, V.M. Anishchik, Y.V. Sveshnikov, V.V. Astashynski, N.T. Kvasov, A.L. Danilyuk, A.V. Punko and Y. Pauleau	**157**	Deposition of nanostructured metal coatings on the modified silicon surfaces in the magnetoplasma compressor
D. Krupa, J. Baszkiewicz, B. Rajchel, A. Barcz, J.W. Sobczak and A. Biliński	**161**	Effect of sodium-ion implantation on the corrosion resistance and bioactivity of titanium
R.E. Hurley, S. Suder and H.S. Gamble	**167**	Ion implantation of hydrogen and helium into silicon wafers for layer transfer in devices
R. Kögler, F. Eichhorn, A. Mücklich, W. Skorupa, C. Serre and A. Perez-Rodriguez	**177**	Effect of excess vacancies in ion beam synthesis of SiC nanoclusters
B. Sartowska, J. Piekoszewski, L. Waliś, W. Szymczyk, J. Stanisławski, L. Nowicki, R. Ratajczak, M. Kopcewicz, J. Kalinowska, M. Barcz and F. Prokert	**181**	Modification of the near surface layer of carbon steels with intense argon and nitrogen plasma pulses

K. Głuch, S. Feil, V.G. Hasan, S. Matt-Leubner, T. Tepnual, O. Echt, V. Grill, P. Scheier and T.D. Märk	**187**	Coulomb explosion of $si1.gif C_7H_7^{2+}$ ions produced by electron impact ionization of toluene
L. Wójcik and A. Markowski	**193**	Ion–molecule reaction in pure H_2S
W. Jung, A. Misiuk and C.A. Londos	**199**	Pressure stimulated creation of oxygen-related defects in oxygen-implanted and neutron-irradiated silicon
M. Barlak, W. Olesińska, J. Piekoszewski, M. Chmielewski, J. Jagielski, D. Kaliński, Z. Werner and B. Sartowska	**205**	Ion implantation as a pre-treatment method of AlN substrate for direct bonding with copper
F.P. Korshunov, N.E. Zhdanovich, V.I. Karas and I.G. Marchenko	**211**	High-temperature annealing of electron-irradiated high-voltage diode structures on neutron transmutation-doped Si
J. Martan, G. Przybylski, R. Tabaka and Z.W. Kowalski	**217**	Fractal analysis of roughness profile induced by ion bombardment of metal surfaces
R. Khalfaoui, C. Benazzouz, A. Guittoum, N. Tabet and S. Tobbeche	**223**	Irradiation-induced silicide formation in the ion beam-mixed Au/Si(100) system at room temperature
J. Narojczyk, Z. Werner, J. Piekoszewski and W. Szymczyk	**229**	Effects of nitrogen implantation on lifetime of cutting tools made of SK5M tool steel
L. Wójcik and A. Markowski	**235**	Mass spectrometric study of ion/molecule reaction in methane and ammonia mixtures
E.B. Bojko, C. Karwat, K. Kiszczak, M. Kolasik, T. Kołtunowicz, F.F. Komarov, A.F. Komarov, C. Kozak, A. Wdowiak and P. Żukowski	**241**	Deposition of monoatomic and compound metal layers by the dynamic ion mixing
V.G. Zavodinsky, A.A. Gnidenko, A. Misiuk and J. Bak-Misiuk	**247**	Ab initio simulation of high pressure influence on He–H interaction in silicon
D.I. Brinkevich, V.B. Odzhaev, V.S. Prosolovich and Y.N. Yankovski	**251**	Formation of radiation defects in silicon at high-energy implantation
M. Rubel, J.P. Coad and D. Hole	**255**	Accelerator-based ion beam analysis of fusion reactor materials
B. Jaroszewicz, K. Domanski, D. Tomaszewski, P. Janus, A. Kudla, B. Latecki, A. Kociubinski, M. Nikodem, J. Katcki, M. Wzorek, J. Marczewski and P. Grabiec	**263**	Application of ion implantation for mono-Si piezoresistors manufacturing in silicon MEMS technology
A. Saad, A. Mazanik, A. Fedotov, J. Partyka, P. Węgierek and P. Żukowski	**269**	Influence of low-energy ion-beam treatment by hydrogen on electrical activity of grain boundaries in polycrystalline silicon
R.A. Khmelnitskiy, E.V. Zavedeev, A.V. Khomich, A.V. Gooskov and A.A. Gippius	**273**	Blistering in diamond implanted with hydrogen ions
A.M. Abdul-Kader, A. Turos, J. Jagielski, L. Nowicki, R. Ratajczak, A. Stonert and M.A. Al-Ma'adeed	**281**	Hydrogen release in UHMWPE upon He-ion bombardment

A. Turos, A.M. Abdul-Kader, S. Podsiadło, B. Strojek, I. Strzałkowski and D. Grambole	**285**	Hydrogen behaviour in novel materials for spintronic: GaFeN co-doped with Mg, Si and Al
M. Ćwil and P. Konarski	**291**	Ion beam shadowing effects in SIMS depth profile analysis of MBE-grown nanostructures
P. Konarski, J. Hałuszka, M. Ćwil, I. Iwanejko, K. Kaczorek, J. Gaweł, K. Pisiewicz, A. Lesiak-Bednarek and H. Strugała-Stawik	**297**	Ion beam analysis of urban aerosol micro and nanoparticles compared with environmentally related children diseases in two Polish towns
F. Eichhorn, J. Gaca, V. Heera, N. Schell, A. Turos, H. Weishart and M. Wojcik	**303**	Structural studies on ion-implanted semiconductors using X-ray synchrotron radiation: Strain evolution and growth of nanocrystals
M. Kowalski, J. Partyka, P. Węgierek, P. Żukowski, F.F. Komarov, A.V. Jurchenko and D. Freik	**311**	Frequency-dependent annealing characteristics of the implant-isolated GaAs layers
G. Zschornack, S. Landgraf, F. Grossmann, U. Kentsch, V.P. Ovsyannikov, M. Schmidt and F. Ullmann	**319**	A low energy ion beam line for highly charged ions
M. Wiertel, E. Taranko and R. Taranko	**325**	Charge transfer dynamics in atom scattering on atoms adsorbed on metal surface: Effect of electron correlations
A.I. Ryabchikov, I.A. Ryabchikov and I.B. Stepanov	**331**	Development of filtered DC metal plasma ion implantation and coating deposition methods based on high-frequency short-pulsed bias voltage application
I.S. Tashlykov and O.G. Bobrovich	**337**	Radiation damage of Si wafers modified by means of thin layer ion assisted deposition
R. Khalfaoui and S. Tobbeche	**341**	Determination of atomic depth profile in ion-beam mixed bilayer systems from the Rutherford backscattering data
E. Jartych, A. Calka, A. Smolira and L. Michalak	**347**	Hydrogen-induced phase transformations in nanostructured graphite made by controlled ball milling
F.F. Komarov, L.A. Vlasukova, V.N. Yuvchenko, T.V. Petlitzkaya and P. Zukowski	**353**	Peculiarities of the track formation in InP and GaAs crystals
F.F. Komarov, L.A. Vlasukova, O.M. Milchanin, P.I. Gaiduk, V.N. Yuvchenko and S.S. Grechnyi	**361**	Ion-beam formation of nanopores and nanoclusters in SiO_2
L. Pranevicius, C. Templier, L.L. Pranevicius and D. Milcius	**367**	Influence of surface barriers on hydrogen storage in MgAl films on permeable stainless steel membranes
P.I. Gaiduk	**375**	Discontinuous tracks in relaxed SiGe alloy layers: Formation and thermal evolution
V.V. Ilyina, N.V. Makarets and V.V. Moskalenko	**381**	Influence of higher semi-invariants on the fitting parameters of implanted ions distribution
A. Zeleák, M. Gregor, M. Štefečka, V. Gašparík and P. Kováč	**385**	Preliminary results on the DECRIS 14 - 2m ECR heavy-ion injector source
J. Baranowska, E. Kusior, V. Amigo and K. Szczeciński	**389**	Surface modification of austenitic steel by low-temperature plasma

M. Laurikaitis, J. Čyvienė and J. Dudonis	**395**	Deposition of $Zr–ZrO_X$ and $Y–Y_XO_Y$ films by reactive magnetron sputtering
L. Thomé, J. Jagielski, L. Nowicki, A. Turos, A. Gentils and F. Garrido	**401**	Use of ion channeling for the study of the damage induced in ceramics by ion irradiation
J. Jagielski	**409**	Friction properties of ion-beam modified materials: Where can we search for practical applications of ion implantation?
R. Jakieła, A. Barcz, E. Wegner and A. Zagojski	**417**	Diffusion and activation of Zn implanted into InP:S
K. Nowakowska-Langier, K. Zdunek and M. Kopcewicz	**423**	Phase structure of the Fe–Ti layers produced by the IPD method
R. Hellborg, M. Kiisk, P. Persson and K. Stenström	**427**	Vacuum in an accelerator system—calculations and measurements
M. Rosiński, J. Badziak, F.P. Boody, S. Gammino, H. Hora, J. Krása, L. Láska, A.M. Mezzasalma, P. Parys, K. Rohlena, L. Torrisi, J. Ullschmied, J. Wołowski and E. Woryna	**435**	Application of laser ion source for ion implantation technology
B. Pawłowski, M. Petrascu, J. Czerbniak, D. Pantelica and M. Moneta	**439**	Experimental results for change of H and Li ions stopping in metal foils with temperature
A.I. Ryabchikov, I.A. Ryabchikov, I.B. Stepanov and D.O. Sivin	**445**	Recent advances in surface processing with the filtered DC vacuum-arc plasma
M. Andreyev, V. Anishchik, L. Markova and T. Kuznetsova	**451**	Ion-beam coatings based on Ni and Cr with ultradispersed diamonds—structure and properties
D. Machajdík, A.P. Kobzev and K. Fröhlich	**455**	Complementarity of X-ray diffraction and RBS in thin film characterization
A. Wiatrowski, B. Boratyński, S. Prucnal, Z. Synowiec and J. Żuk	**463**	Proton implant isolation in GaN
M. Moneta and B. Pawłowski	**467**	Ion stopping cross-section at ferro-paramagnetic phase transition
R. Fedaruk and P. Żukowski	**473**	Dressed state EPR nutations of E_1' centers in neutron-irradiated quartz
L.L. Pranevicius, D. Milcius and V. Girdauskas	**477**	Plasma hydrogenation of MgAl thin films and H_2 effusion
N.N. Cherenda, V.V. Uglov, V.M. Anishchik, A.K. Stalmashonak and V.M. Astashinski	**483**	Structure-phase transformations in high-speed steel treated by compression plasma flow
V.V. Uglov, V.M. Anishchik, N.N. Cherenda, A.K. Stalmashonak, V.M. Astashinski, A.M. Kuzmickii, E.A. Kostyukevich and A.V. Kovyazo	**489**	Mixing of chromium/carbon steel by compressive plasma flows
E.B. Bojko, C. Karwat, K. Kiszczak, M. Kolasik, T. Kołtunowicz, F.F. Komarov, C. Kozak, F.A. Romaniuk, A. Wdowiak and P. Żukowski	**495**	Electrical properties of contacts covered with multicomponent coatings by the dynamic ion mixing

H.W. Kunert, T. Maurice, J. Barnas, J. Malherbe, D.J. Brink and L. Prinsloo	**503**	Raman and photoluminescence spectroscopy from n- and p-type 6H-SIC alpha-particle irradiated
O. Anan'yina and O. Yanovs'ky	**509**	Simulation of phosphorus ions interaction with Ge(100)-2 × 1 surfaces
T. Wilczyńska, R. Wiśniewski, K. Wieteska and B. Słowiński	**515**	Influence of deep-implanted Kr ions on resistivity of pressure manganin sensors
D.I. Tetelbaum, A.N. Mikhaylov, O.N. Gorshkov, A.P. Kasatkin, A.I. Belov, D.M. Gaponova and S.V. Morozov	**519**	Ion beam synthesis of Si nanocrystals in silicon dioxide and sapphire matrices—the photoluminescence study
I. Azarko, E. Kozlova, V. Odzhaev, O. Yankovsky, O. Ignatenko and V. Shipilo	**525**	Irradiation of cubic boron nitride microcrystals of different dopant-faulted structure with neutrons of fission spectrum
I.I. Tashlykova-Bushkevich	**529**	RBS analysis of rapidly solidified Al–Si–Ti alloy with Fe and Ni dopes
J. Paluszyński and W. Słówko	**533**	Surface reconstruction with the photometric method in SEM
S. Han, H.-Y. Chen and H.C. Shih	**539**	Argon ion beam voltage in a dual ion beam sputtering system influence on the aluminum nitride films microstructure
V.M. Anischik, V.V. Uglov, S.V. Zlotski, P. Konarski, M. Cwil and V.A. Ukhov	**545**	SIMS investigation of nitride coatings
M.A. Lourenço, M. Milosavljevic, S. Galata, M.S.A. Siddiqui, G. Shao, R.M. Gwilliam and K.P. Homewood	**551**	Silicon-based light emitting devices
M. Huleihel, M. Karpasas, M. Talyshansky, Y. Souprun, Y. Doubijanski and V. Erukhimovitch	**557**	Mass spectroscopic and IR spectroscopic evaluation of abnormal biological samples
I. Shimoyama, Y. Baba and T. Sekiguchi	**563**	Synthesis of single-phase carbon nitride film prepared by hot implantation
W. Wierzchowski, K. Wieteska, W. Graeff, A. Turos and R. Grötzschel	**569**	X-ray diffraction studies of GaAs implanted with 1.5MeV Se+ ions
A.V. Khomich, R.A. Khmelnitskiy, V.V. Kononenko, E.V. Zavedeev, S.M. Pimenov, V.G. Ralchenko and V.I. Konov	**577**	Comparison of laser and thermal annealing of diamonds implanted with deuterium
A.V. Khomich, V.I. Kovalev, E.V. Zavedeev, R.A. Khmelnitskiy and A.A. Gippius	**583**	Spectroscopic ellipsometry study of buried graphitized layers in the ion-implanted diamond
V.M. Anishchik, V.V. Astashynski, V.V. Uglov, J.A. Fedotova, J. Stanek and A.M. Kuzmitski	**589**	Mössbauer investigations of iron under the action of hydrogen and nitrogen compressive plasma flows
A. Grigonis, Ž. Rutkūnienė, V. Kopustinskas, G.J. Babonas and A. Rėza	**593**	Investigation of optical properties of a-C:H films deposited from acetylene using direct ion beam deposition method
A.A. Youssef, P. Budzynski, J. Filiks and Z. Surowiec	**599**	Improvement of tribological properties of aluminum by nitrogen implantation
Z. Wroński and J. Sielanko	**605**	Glow discharge sputtering of two-component cathode target

A. Kuzmichev, O. Bevza, H. Steffen and R. Hippler	**611**	Impact excitation of MF magnetron discharge for PVD processes
F.F. Komarov, A.V. Leontyev, A.V. Khomich and V.I. Kovalev	**617**	Optimization of the formation process of dielectric microwaveguides on the basis of polymer/SiO_2/Si systems using ion irradiation
L. Bellemo, R. Carta, S. Daliento, L. Gialanella, B.N. Limata, L. Mele, M. Romano, A. Sanseverino and P. Spirito	**623**	Electrical measurement of the lattice damage induced by *si2.gif* α-particle implantation in silicon
J. Staňo, V.A. Skuratov, M. Žiška and P. Kováč	**627**	Radiation-induced defects in MOS structures after irradiation with high-energy Ar, Kr, Bi heavy ions
A. Pelc, W. Sailer, P. Scheier and T.D. Märk	**631**	Generation of (M–H)− ions by dissociative electron attachment to simple organic acids M
K. Bederski	**635**	High pressure investigations of positive ion–molecule reactions in a mixture of C_3H_6 and Ne
Z. Wroński	**641**	Dissociation of nitrogen in the plasma-cathode interface of glow discharges
M. Turek, A. Drożdziel, K. Pyszniak and J. Sielanko	**649**	Extraction of the ion beam from hollow cathode ion source. Experiment and computer simulation
A. Smolira, S. Ptasińska, M. Smolira and L. Michalak	**655**	Matrix-assisted laser desorption/ionization detection of hemoglobin from long-stored samples of human blood
M. Kąc, M. Toulemonde, J. Jaworski, J. Juraszek, R. Kruk, S. Protsenko, V. Tokman and M. Marszałek	**661**	Swift heavy-ion modification of the interface structure in Fe/Cr multilayers
X.Q. Cheng, J.M. Sun, R. Kögler, W. Skorupa, W. Möller and S. Prucnal	**667**	Photoluminescence of Er-doped SiO_2 layers containing Si nanoclusters using dual ion implantation and annealing
W. Skorupa, W. Anwand, D. Panknin, M. Voelskow, R.A. Yankov and T. Gebel	**673**	Advanced thermal processing of semiconductor materials in the millisecond range
P. Tarkowski, P. Budzynski and W. Kasietczuk	**679**	Adhesive character of wear processes in nitrogen-implanted iron
P. Budzynski, J. Filiks, P. Żukowski, K. Kiszczak and M. Walczak	**685**	Effect of mixed N and Ar implantation on tribological properties of tool steel
S. Prucnal, X.Q. Cheng, J.M. Sun, R. Kögler, J. Żuk and W. Skorupa	**693**	Optical and microstructural properties of doubly Ge–Si implanted SiO_2 layers
	III	VOLUME CONTENTS
	IX	AUTHOR INDEX